SUMIX

09/18/2024



Polaris X

High-end microscope for detailed inspection of connector endface.

Polaris X is a benchtop system for visual inspection, analysis and certification of single and multi-fiber optic connectors.

Designed for critical examination of the polished fiber end faces, Polaris X may serve as a reference system both on the production floor and in laboratory settings.



Single fiber | Multi-fiber | Auto focus | 0.2 µm defect size detection | High resolution | Scratch detection | Industry standards | PASS/FAIL verdict

Features

Maximum contrast and resolution for accurate inspection

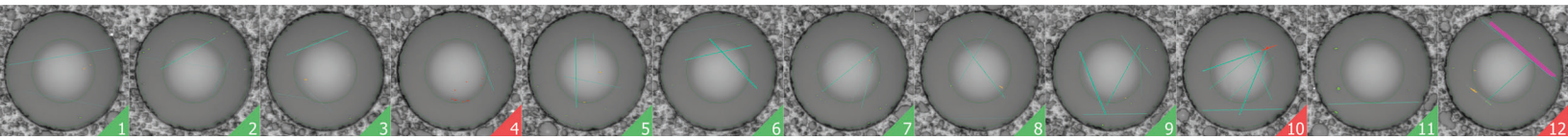
Detect the finest defects as small as 0.2 µm in diameter and scratches as small as 0.4 µm in width.

Longer working distance to increase a variety of tested objects

Inspect not only patch cords but also ODC connectors and MPO connectors in adapters and cassettes.

Automated movement along a multi-fiber endface

No manual shifting, no guesswork about the fiber number, no missed fibers.



MPO connector endface tested on Polaris X.

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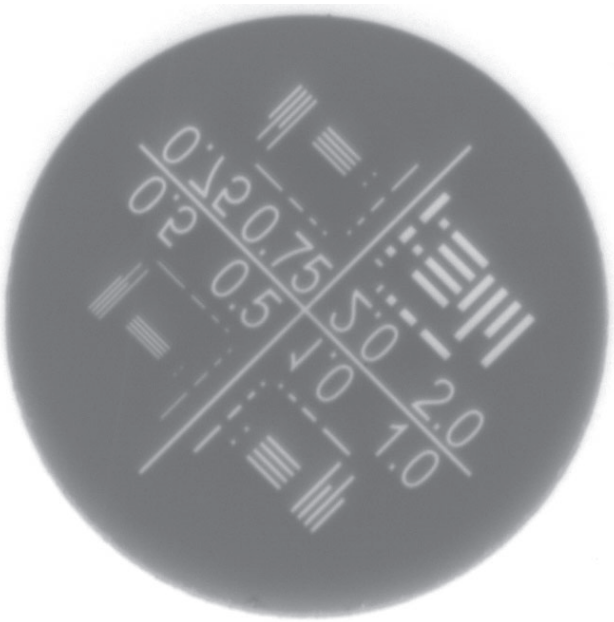
弊社ホームページ QR コード

https://www.high-tech.co.jp/

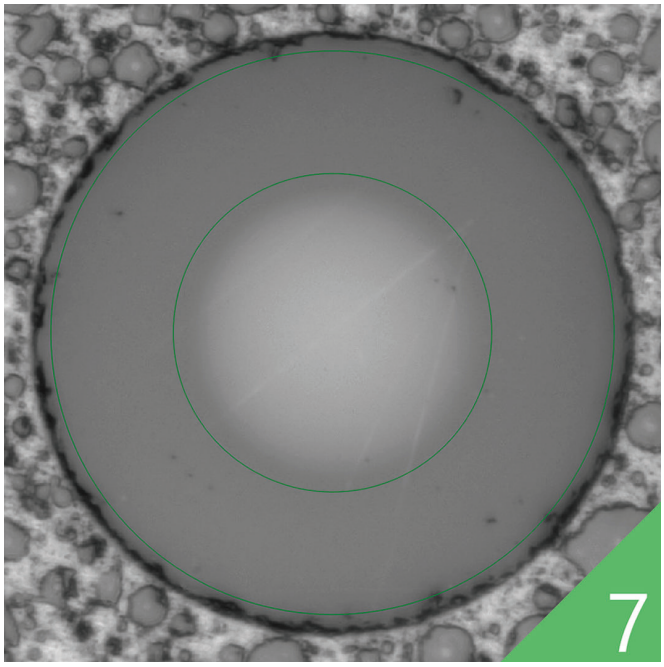
Specification

Field of view:	0.76 × 0.43 mm
Inspection field:	6.4 mm × 6.4 mm* (MTP/MPO connector)
Defect size detection:	0.2 µm
Effective optical resolution:	0.52 µm (according to MTF calculations)
Magnification:	1384×, calculated for 24" screen (1920 × 1080)
Camera resolution:	0.2 µm/px
Illumination wavelength:	470 nm
Focus:	automatic / manual
Focusing range:	± 3 mm
Camera type:	monochrome, 8 MP
Data transfer:	USB 3.0 cable, detachable
Power source:	12 V AC adapter
Dimensions (H×W×L):	129 × 173 × 259 mm (5.08 × 6.81 × 10.2 inches)
Weight:	5.2 kg (11.46 lbs)
Connectors inspected:	SC, FC, ST, LC, MU, Arinc, ODC, MTP®/MPO connectors and cassettes, bare fiber

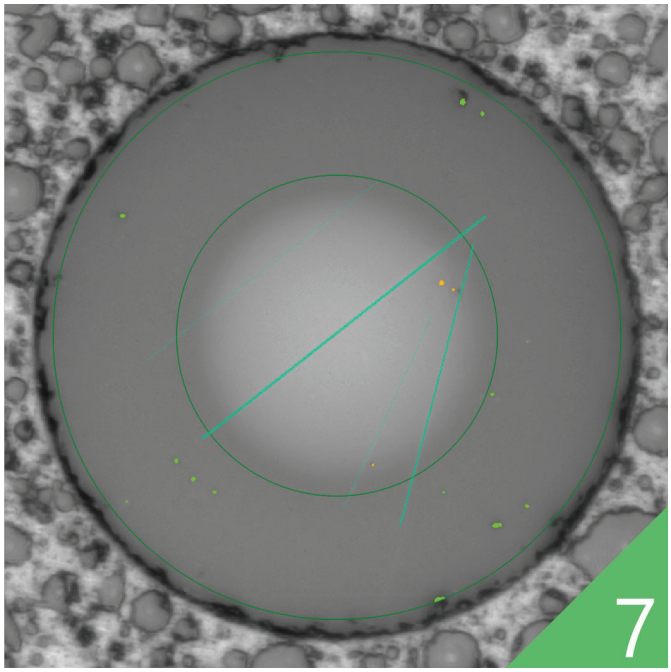
* Due to fully automatic x/y scanning



Endface of a reference test-object demonstrating the resolution of Polaris X. The width of etched lines and the distance between them is defined by the value in microns in the corresponding quadrant.



Live view of a sample MPO fiber with a low-intensity scratch and small defects.



Sample MPO fiber with mapped anomalies identified by the software.